IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No	o10/097,025
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Inventor	Trung Tri Doan
Assignee	Micron Technology, Inc.
Priority Group Art Unit	
Priority Examiner	Karla A. Moore
Attorney's Docket No	Ml22-2471
Title	Atomic Layer Deposition Apparatus and Method

PRELIMINARY AMENDMENT

To:

Mail Stop Patent Application Commissioner for Patents

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Please enter the following amendments prior to examining the aboveidentified application.

<u>AMENDMENTS</u>